

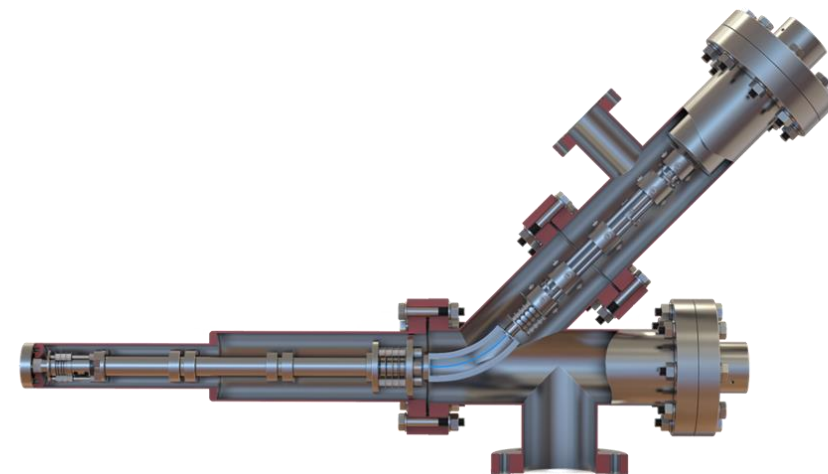
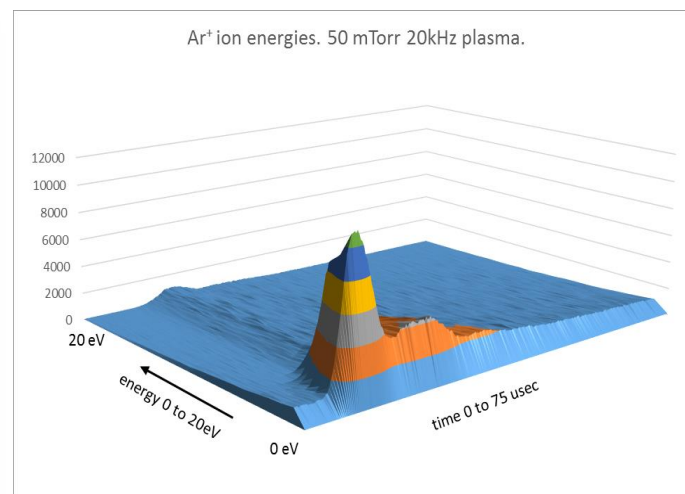
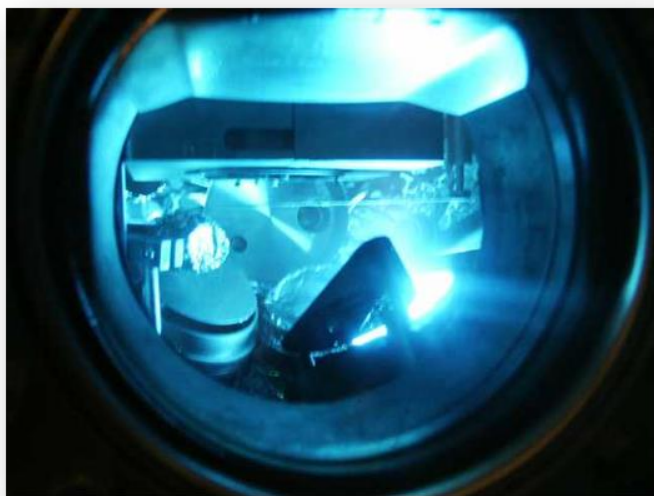
# Hidden EQP Series

Mass/Energy Analysers for Plasma Diagnostics  
and Characterisation

# EQP Series Overview

The Hiden EQP Series are **advanced plasma diagnostic tools** with combined **high transmission ion energy analyser** and **quadrupole mass spectrometer**, acquiring both mass spectra at specified ion energies and ion energy distributions of selected plasma ions.

The EQP series includes a range of quadrupole mass spectrometers with a choice of mass range and performance for a variety of plasma applications.



# EQP Series Overview

The Hiden EQP Series is expanded to include new mass range options as well as Hiden's highest performing, **20mm** rod diameter quadrupole.

## **EQP-6** – 300, 510 amu

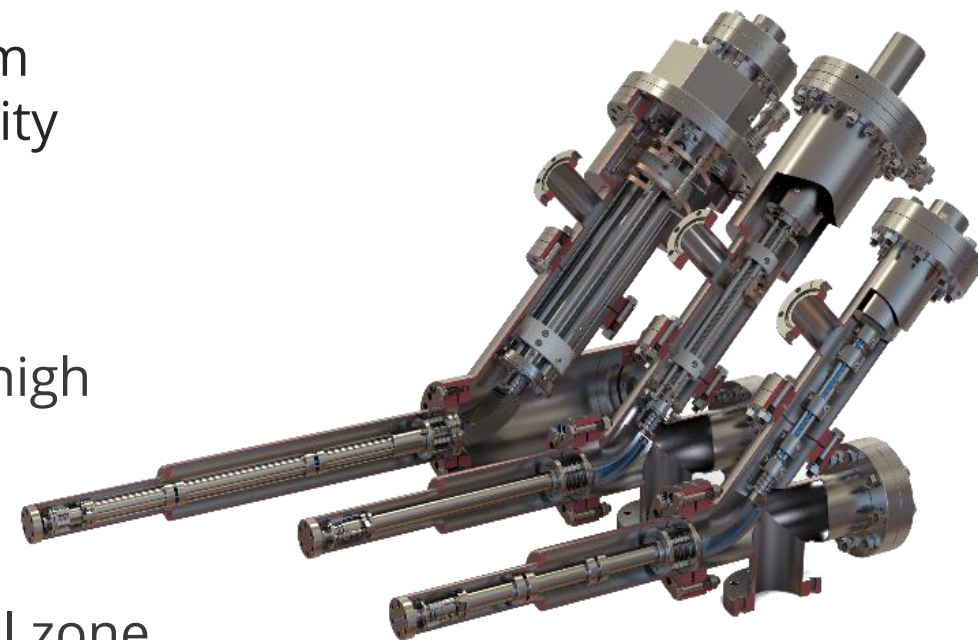
The most cost effective of the series, the 6 mm diameter EQP-6, for high sensitivity and stability measurements of plasma species.

## **EQP-9** – 50, 300, 510, 1000, 2500, 5000 amu

Mass range options for ultra high stability or high mass measurements.

## **EQP-20** – 20/200 amu

Features Hiden's 20 mm quadrupole with dual zone operation for ultra high resolution low mass analysis.



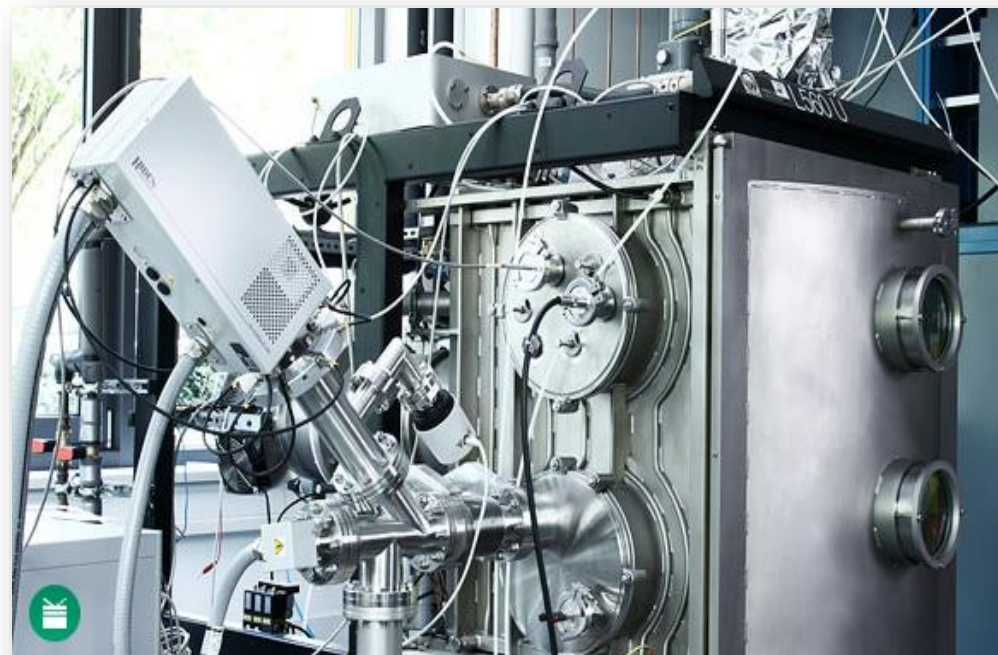
# Features

- Sub PPM detection of plasma ions, neutrals and radicals.
- Ion Energy Analysis, 0-100 eV and 0-1000 eV energy range versions are available.
- Positive and Negative Ion Analysis.
- Neutral and Radical Species Detection.
- Electron attachment ionisation mode for the study of electro-negative radicals.
- Mass range options: 20, 50, 200, 300, 510, 1000, 2500 or 5000 amu.
- A standard TTL signal gating input is included for time resolved studies.

# Applications

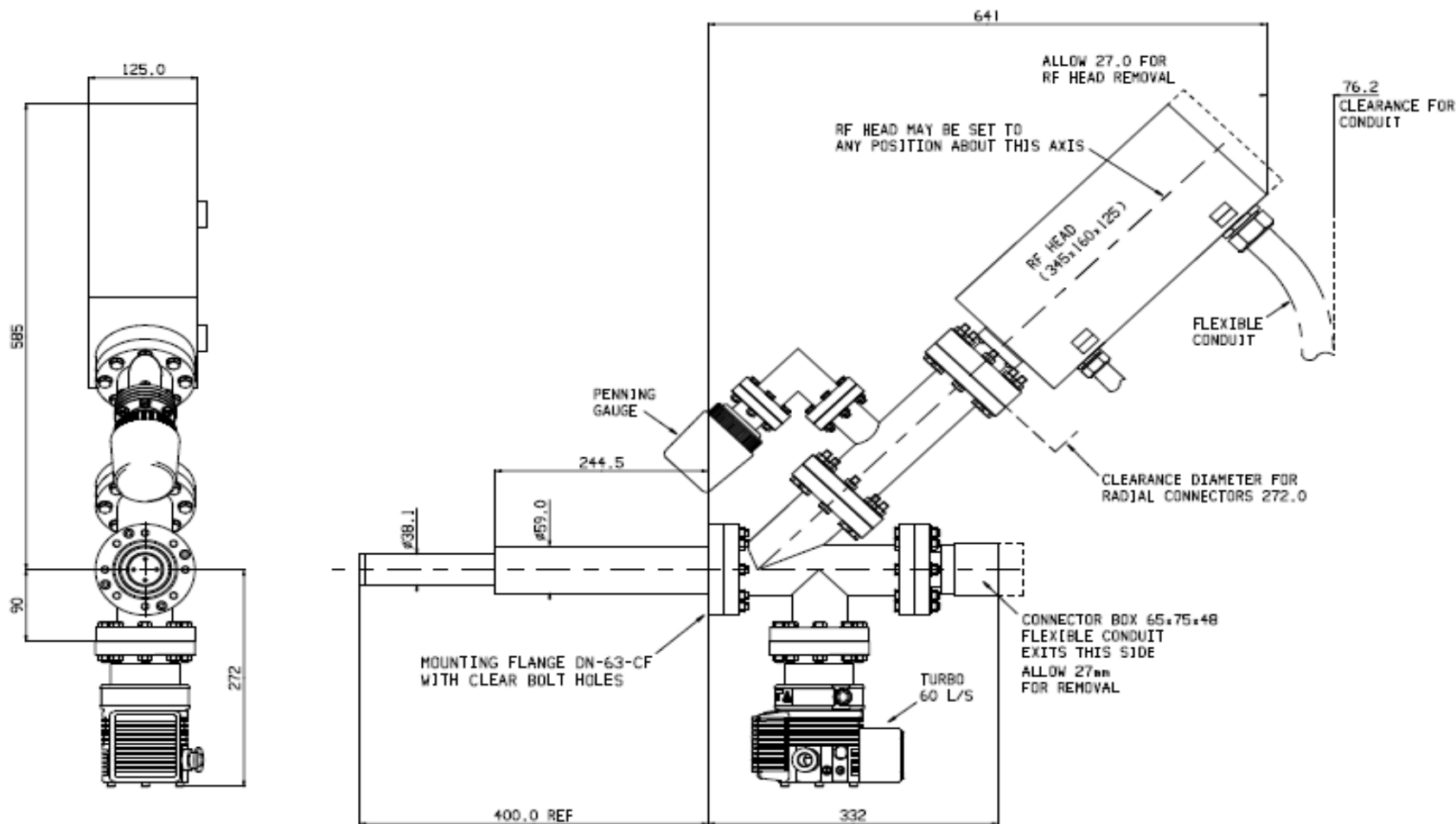
EQP Systems are offered with a range of standard plasma sampling options to provide a non invasive sampling interface for a broad range of plasma applications including:

- ECR- Electron Cyclotron Resonance
- HIPIMS
- Magnetron Discharge
- Helicon Source
- DC Glow Discharge Plasma
- Pulsed Plasma & Laser Ablation
- Parallel Plate - RF Plasma
- ICP- Inductively Coupled Plasma

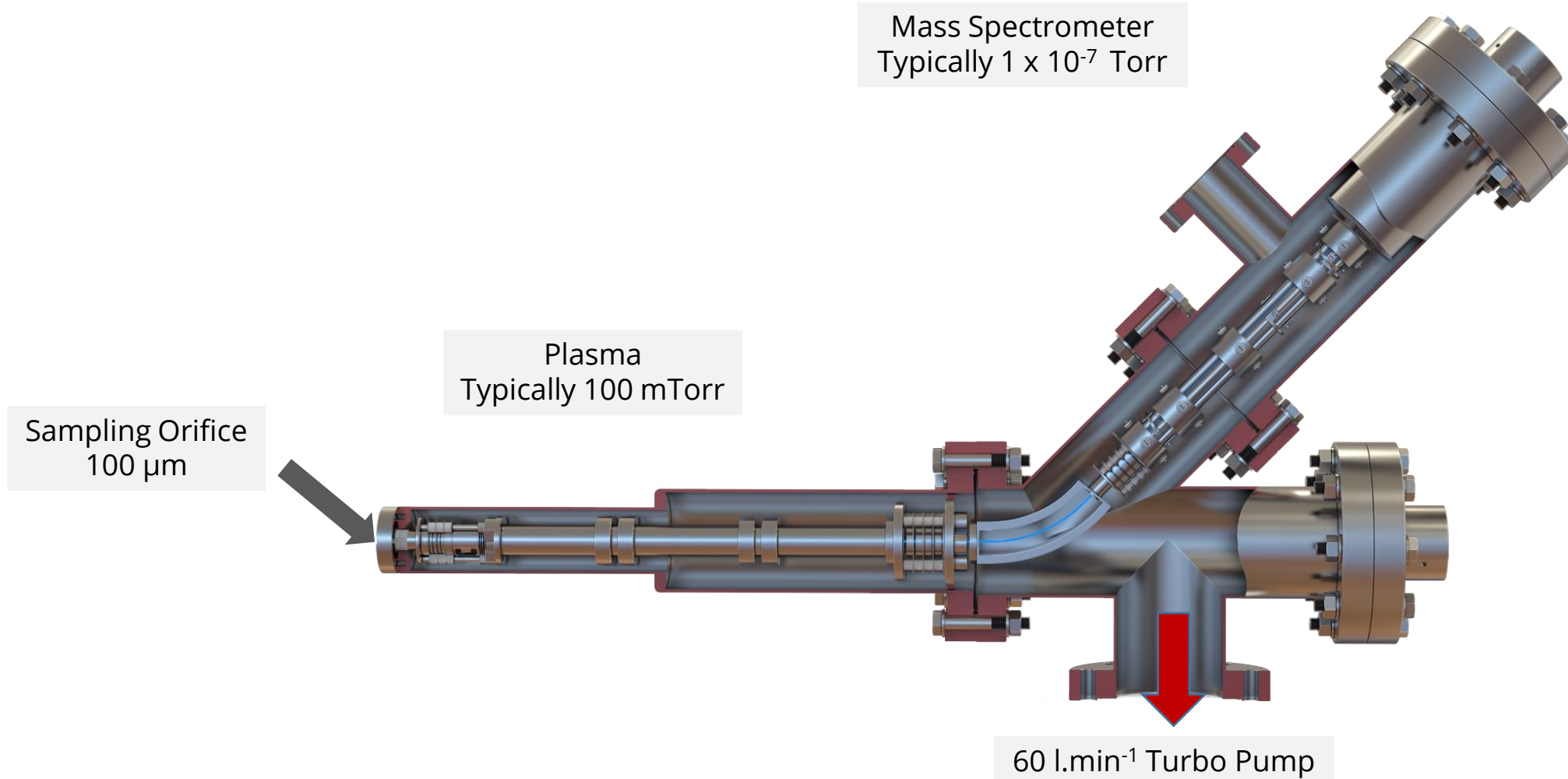




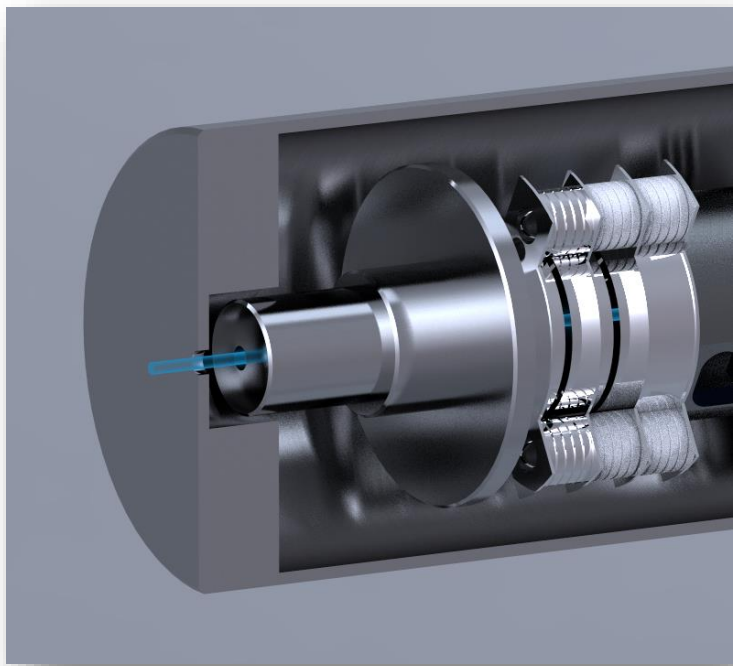
# EQP System Schematic



# Typical Operating Configuration



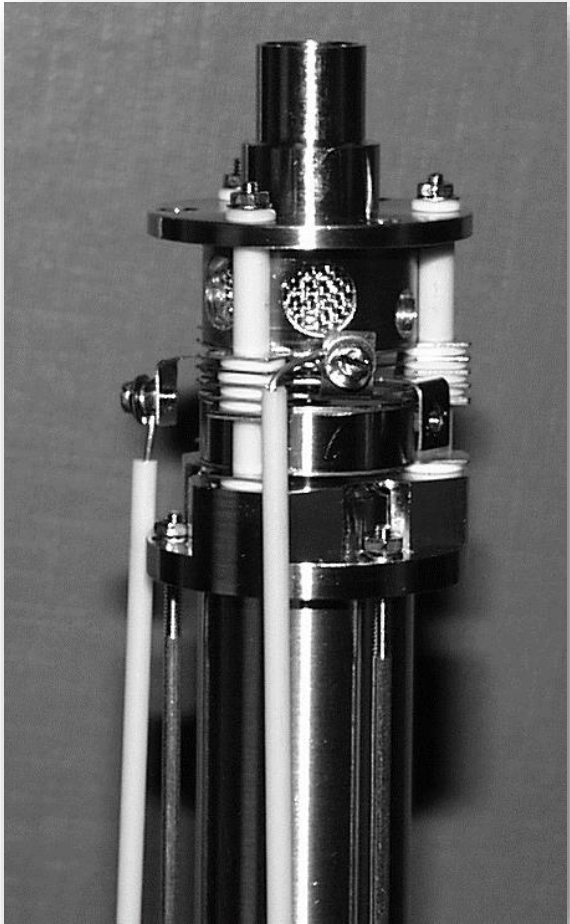
# Laser Drilled Orifice



- User selected dimension from 30 - 300  $\mu\text{m}$ .
- +ve / -ve ions, neutrals or radicals.
- Pre-thinned for optimum sampling.
- Plasma electrode coupling option – allows the user to configure the orifice to exactly follow electrode conditions during operation.



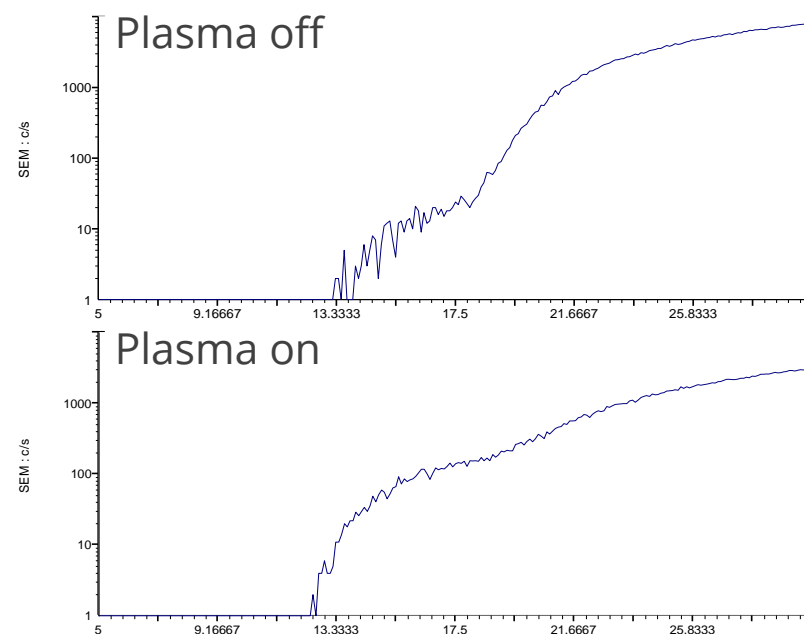
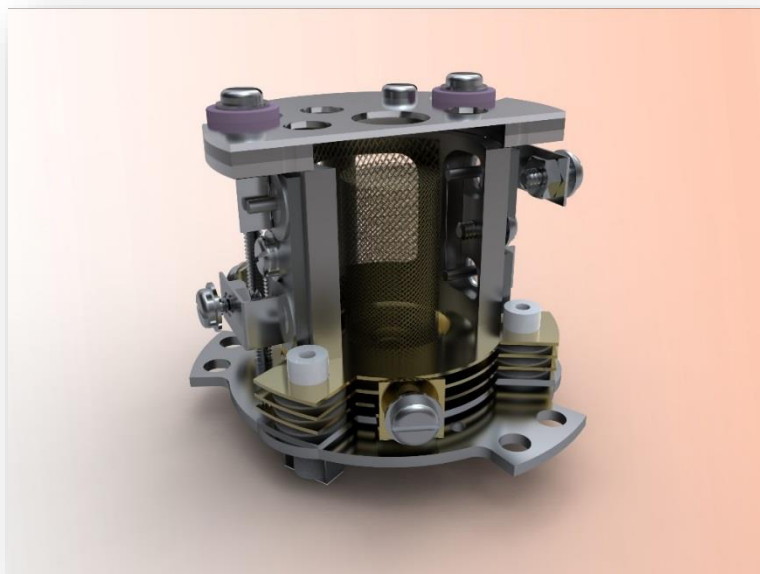
# Extraction Optics



- Software controlled and optimised extraction and focussing optics.
- Discriminates **+ve and -ve** ions as well as **e<sup>-</sup>** and **radicals**.
- **Fully tuneable** for optimal detection.
- Integrated ionisation source.

# Ionisation Source

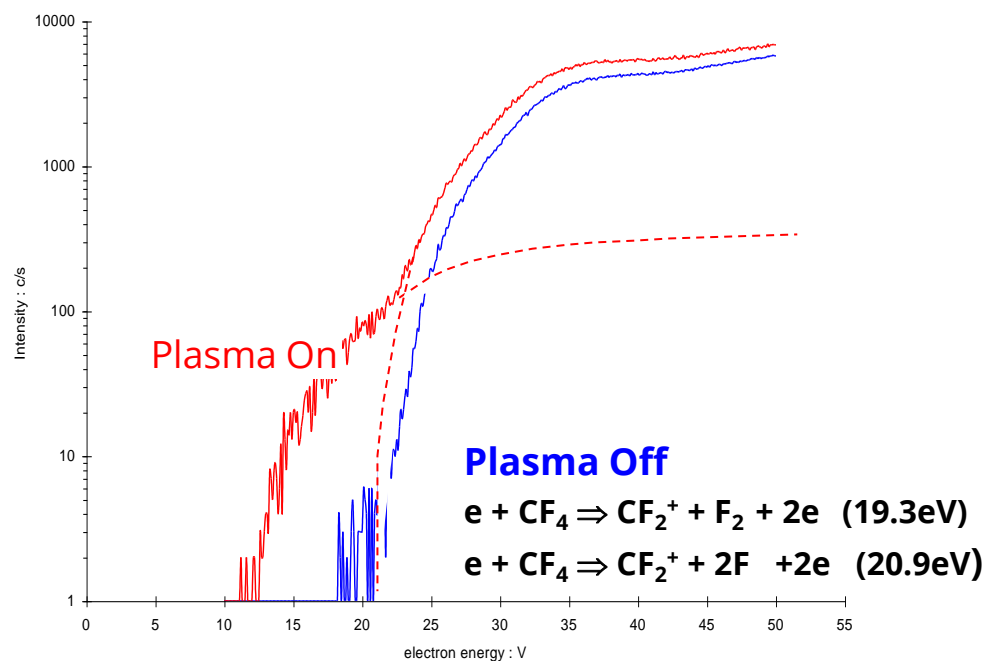
- Fully software controllable **electron energy** (0-150 eV) and thermionic **emission** (0.2-2000  $\mu\text{A}$ ).
- **Electron Impact, Appearance Potential, Soft Ionisation** modes allow for powerful characterisation of the neutral and radical species from the plasma.



# Ion Source Control

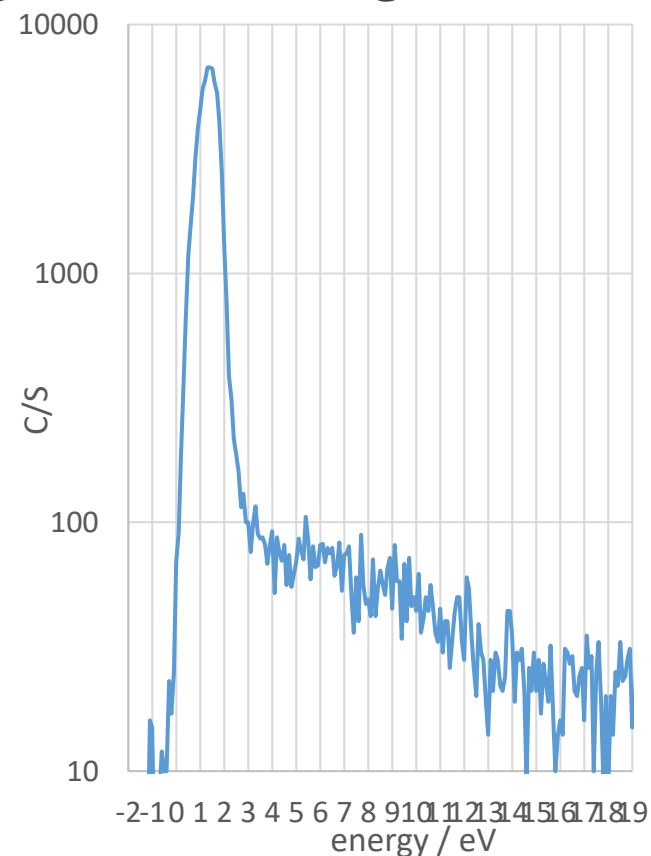
## Electron Energy Scans

Plasma On/Off comparison of the production of CF<sub>2</sub> ions.



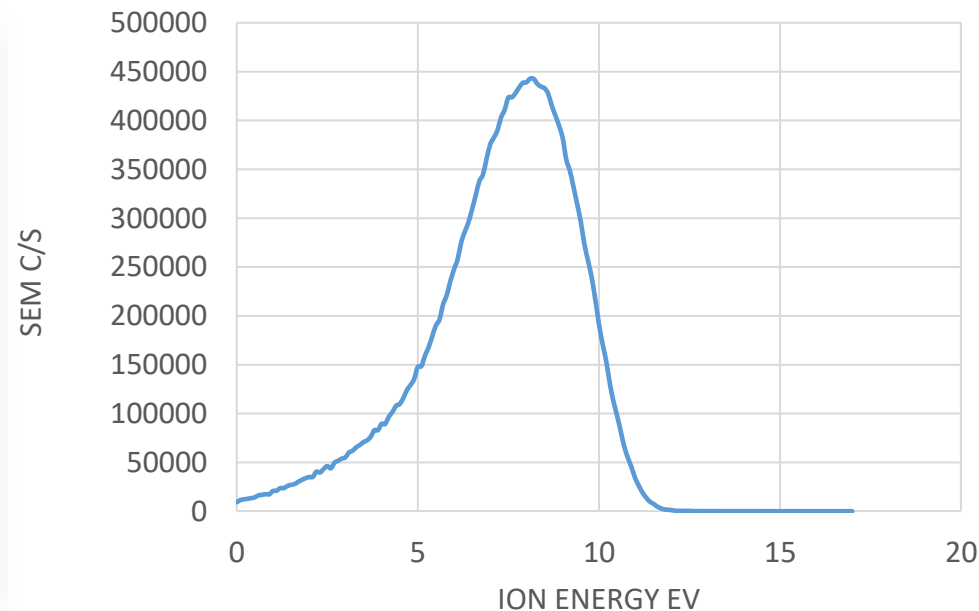
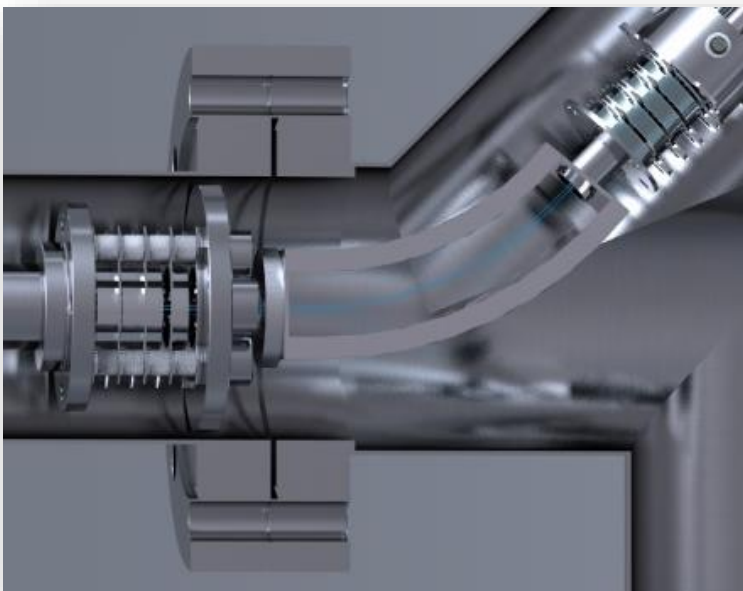
## Energy Scan of Fast Neutrals

Cu Atom Energy Distribution from a DC magnetron discharge.



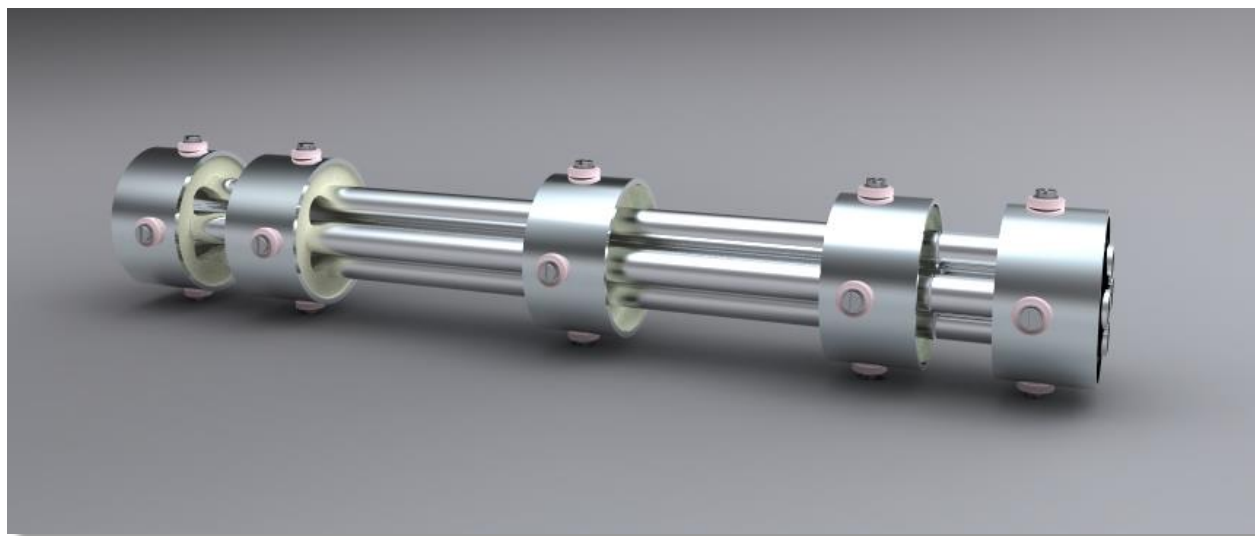
# 45° Electrostatic Sector Energy Analyser

- Constant transmission at all ion energies.
- Minimum perturbation of ion flight path.
- Energy resolution - 0.25 eV FWHM.
- Energy scan at increments from 0.05 eV.
- Floating option available up to 10 KeV.



# Triple Filter Mass Spectrometer

- Strict control over the quadrupole entrance and exit fields provides **enhanced sensitivity** for **high mass transmission** and **increased abundance sensitivity**.
- **Enhanced long-term stability**. The bulk of the deselected ions from the ioniser deposit harmlessly on the RF-only pre-filter stage, minimising contamination on the mass selective primary filter.



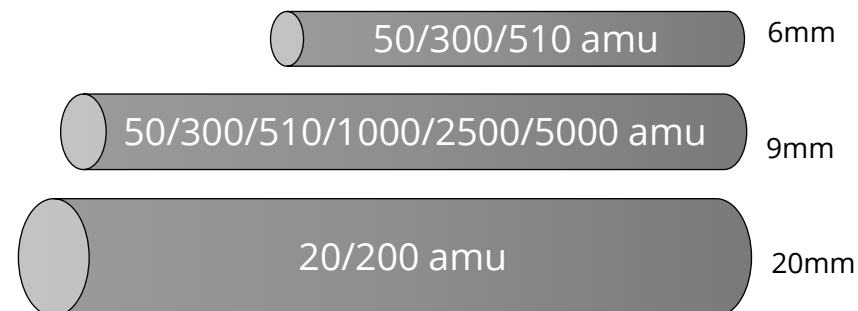


# Quadrupole Diameter

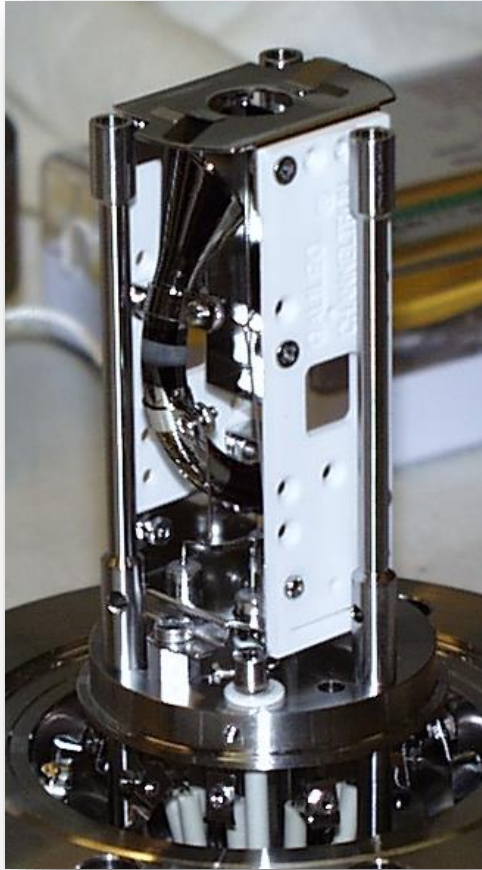
- Configured with **6mm or 9mm**

## What pole diameter do I need?

- Total RF output power is fixed for a given generator.
- Power demand increases dramatically with increasing RF frequency:  
( $\propto \nu^5$ )
- For given **mass, performance improves** with increasing frequency.
- For given tolerances, **transmission** and **mass separation improve** with increasing pole diameter.
- Overall size and cost increase with increasing pole diameter.
- Enlarging pole diameter increases assembly capacitance and limits RF range (increases power losses).



# Secondary Electron Multiplier (SEM) Detector



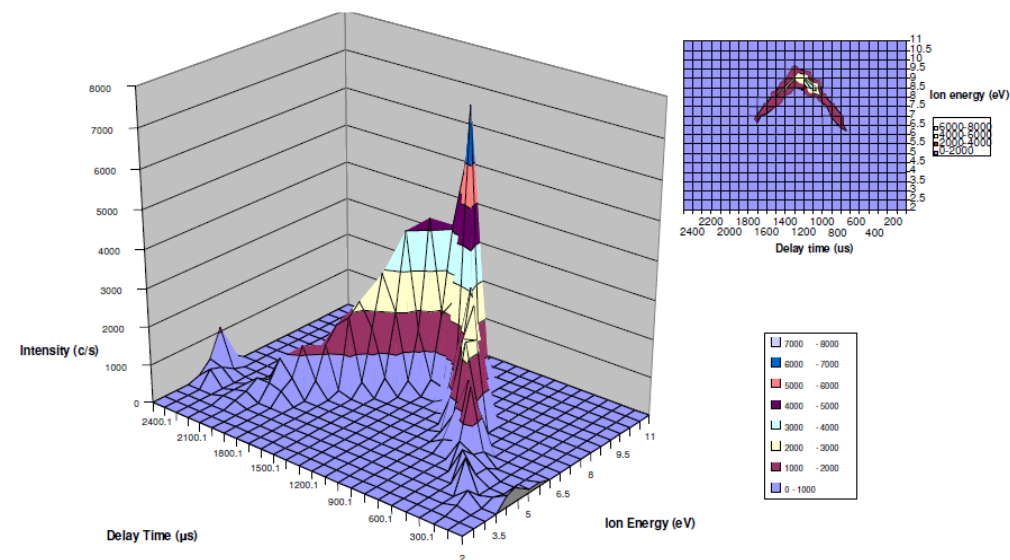
- 7 decade continuous dynamic range.
- 24 bit counter for 1 c/s resolution.
- Faraday Cup option for high density plasmas.
- Signal gating with 50 ns time resolution for energy & mass distributions.
- Comprehensive data export options.

# Programmable Signal Gating

- Signal gating input with **0.1  $\mu\text{s}$**  resolution is standard.
- Enhanced signal gating modes including programmable signal gating and MCS are available as system options or upgrades.
- Programmable signal gating includes foreground and background delay timers to **monitor two time zones** with respect to a relative repeated event.

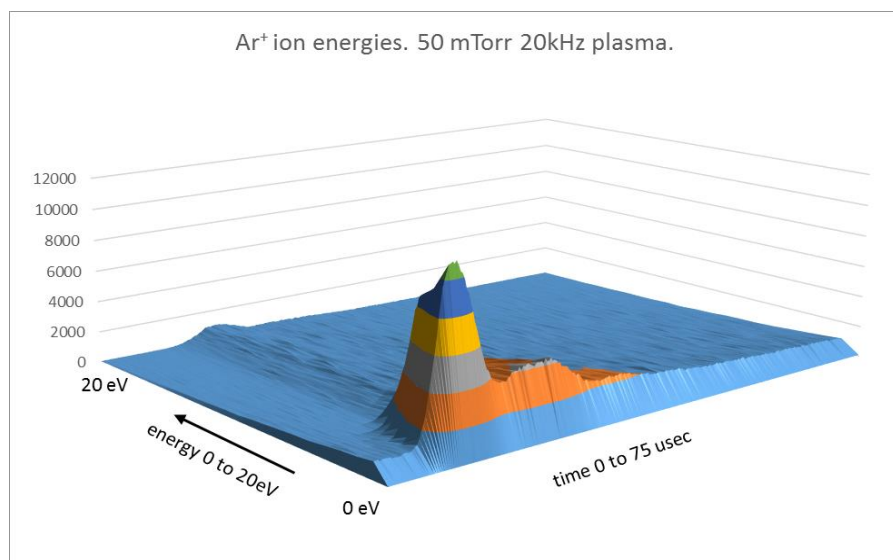
## Features:

- **0.1  $\mu\text{s}$**  minimum gate delay and width.
- Automatic **background subtraction** for modulated molecular beam studies.
- **Ion flight time** measurements.



# Multi-Channel Scalar (MCS) Device

- Optional innovative Multi-Channel Scalar (MCS) device integrated into controller firmware and MASsoft Professional software.
- 6000-bin multichannel scalar resolution offering **50 ns** time resolution.
- Data is **intuitive** to obtain and can be manipulated in external programmes such as Excel and Origin.



Suitable for transient event analysis applications such as:

- Beam chopper inlets.
- Plasma ignition/modulation/extinction experiments.
- Ion flight time measurements.

# Configuration Options

- Analysis through:
  - viewport
  - grounded electrode
  - driven electrode
- High pressure plasmas with double differential pumping.
- Magnetically confined plasmas with optional Mu-metal & radio-metal shielding.
- Analysis of high mass (1000 amu).
- Analysis of high energy (1000 eV).



# Configuration Options

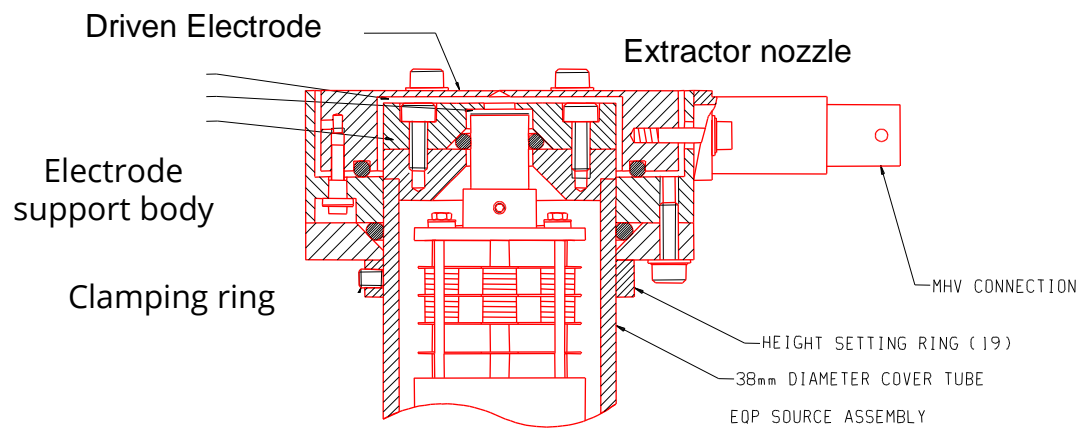


1000 amu EQP with z drive



EQP with RF driven electrode

# Configuration Options



Driven Electrode

Controllable Orifice Cover



# MASsoft Professional control software

The screenshot displays the MASsoft Professional control software interface. The main window shows a 'Real time trend analysis' plot with SEM (y-axis, 10<sup>-12</sup> to 10<sup>-4</sup>) versus Time (x-axis, 08:20 to 41:40). The plot shows several peaks corresponding to different components: Water (yellow), Ammonia (red), Argon (green), Carbon Dioxide (purple), Isopropyl alcohol (cyan), and Methyl Alcohol (blue). A 'Quick Start Tasks' panel is visible on the left, and a 'Scan Editor' panel is on the right. A 'MID Mode' dialog box is open, showing a table of scan parameters.

Component		Scan Parameters								
Name	Mass	Mode	Detector	Range	Au.	Rel Sens	Rel SEM	Colour	Line	Style
Hydrogen	2.00	Unknov	Faraday	-5	✓	0.440	1.000	Aqua	---	Thin sc
Water	18.00	RGA	Faraday	-5	✓	0.900	1.000	Light Green	---	Thin sc
Oxygen	32.00	Unknov	Faraday	-5	✓	0.860	1.000	Red	---	Thin sc
Argon	40.00	RGA	Faraday	-5	✓	1.200	1.000	Blue	---	Thin sc
Pressure	0.40	RGA	Faraday	-5	✓	1.200	1.000	Fuchsia	---	Thin sc

The 'Scan Editor' panel shows a sequence of scans: Scan 1: mass 2.00, Scan 2: mass 18.00, Scan 3: mass 32.00, Scan 4: mass 40.00, and Scan 5: Pressure 0.40. The 'MID Mode' dialog box is open, showing a table of scan parameters and a 'Real time trend analysis' plot.

A multilevel software package allowing both simple control of mass spectrometer parameters and complex manipulation of data plus control of external devices.

# Selected Publications

- [Latest publications](#)
- Negative-ion surface production in hydrogen plasmas: modelling of negative-ion energy distribution functions and comparison with experiments. 2013. A Ahmad et al. *Plasma Sources Sci. Technol.* **22** 025006
- Spatially enhanced Langmuir probe measurements of a magnetically enhanced hollow cathode arc plasma. 2011. B Zimmermann et al. *Surface and coatings technology* **205** 5393-5396
- Quantification of the deuterium ion fluxes from a plasma source. 2011. A Manhard et al. *Plasma Sources Sci. Technol.* **20** 015010
- Advantages of highly ionized pulse plasma magnetron sputtering of silver for improved E. coli inactivation. 2012. O Baghriche et al. *Thin Solid Films* **520** 3567-3573
- Influence of high power impulse magnetron sputtering plasma ionization on the microstructure of TiN thin films. 2011. AP Ehiasarian. *J. Appl. Phys.* **109** 104314

# Selected Hiden EQP Users



- Xi'an Modern Chemistry Institute
  - University d'Orleans
- Southwest Research Institute
  - KRICT
  - INP Greifswald
  - Applied Materials
  - Fraunhofer IWS
- Ruhr-Universität Bochum



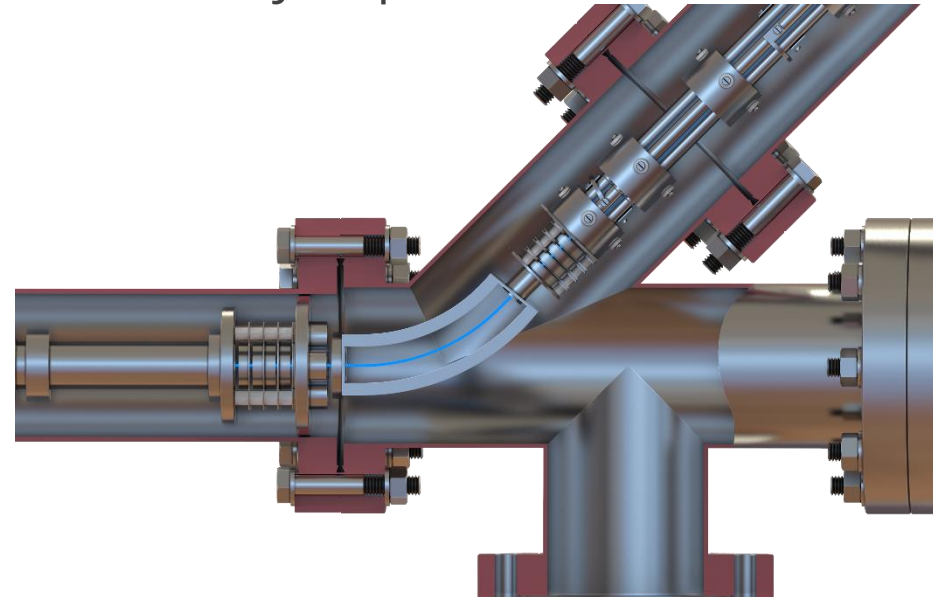
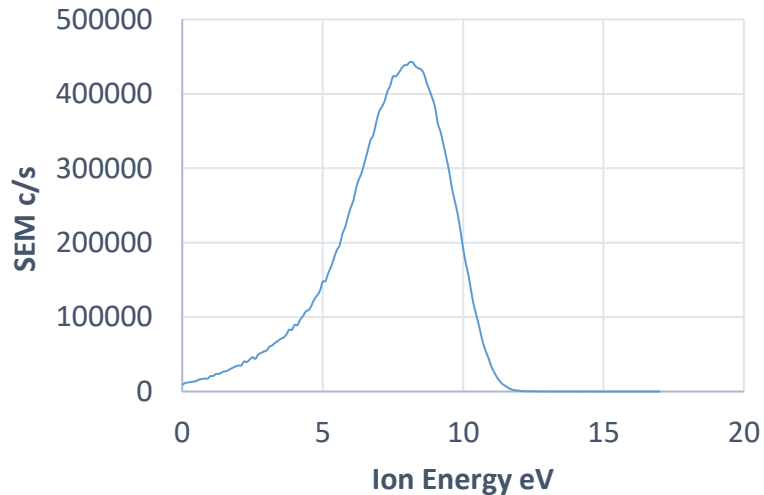
RUHR  
UNIVERSITÄT  
BOCHUM





# Summary

- High performance probe for mass and energy analysis of ions, radicals and neutrals from a plasma.
- A large number of options are available in order to sample from a variety of plasma types.
- The EQP sees use worldwide in a variety of plasma applications.



- 
- A photograph of a modern, two-story office building with a grey facade and large glass windows. The building has a prominent "HIDEN ANALYTICAL" sign on its side. The sky is clear blue, and there are some trees and bushes in the foreground. A large, semi-transparent white circle is overlaid on the left side of the image, containing the text of the list.
- [www.HidenAnalytical.com](http://www.HidenAnalytical.com)
  - The Hiden website is an excellent resource with product pages, brochures, catalogues, product pages with some application notes, presentation and other information.
  - Contact +44 1925 445225 for direct support.